

<b>Notice of References Cited</b>	Application/Control No. 10/683,858		Applicant(s)/Patent Under Reexamination VASHCHENKO ET AL.	
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	C	US-6,555,894	04-2003	Beasom, James D.	257/593
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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